

LASER MICROFABRICATION OF MULTIFUNCTIONAL DEVICES

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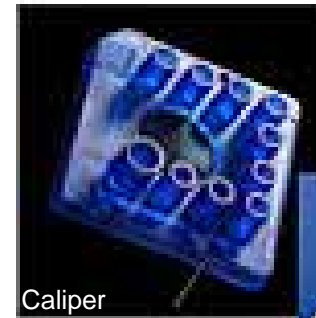
UK Laser Micromachining Centre

“Laser Microprocessing of Challenging Materials and Architectures”
AILU Technology Workshop, Cardiff University, 4 July 2007

BIOTECH CHIPS

Complex multifunctional devices used in:

- Cell manipulation & detection
- Drug discovery
- Chromatography
- Virus detection
- Microarray technology
- Proteomics
- Genomics
- Blood analysis
- Microbiology
- Many aspects of personal healthcare



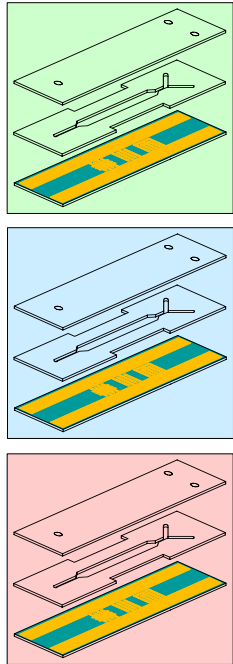
Development phase requires evaluation of numerous designs and concepts → **LASERS**
Medical devices → Stringent validation and regulatory qualifications (high costs to market)
Mature products → Ultrahigh volume production



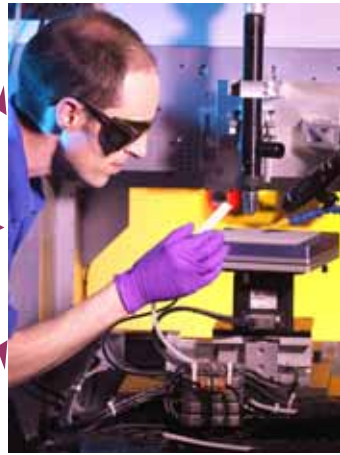
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DEVELOPMENT CYCLE

Designs



Process Development



Manufacture & Assembly



Testing



Batch Production

Laser microfabrication allows rapid implementation of design concepts

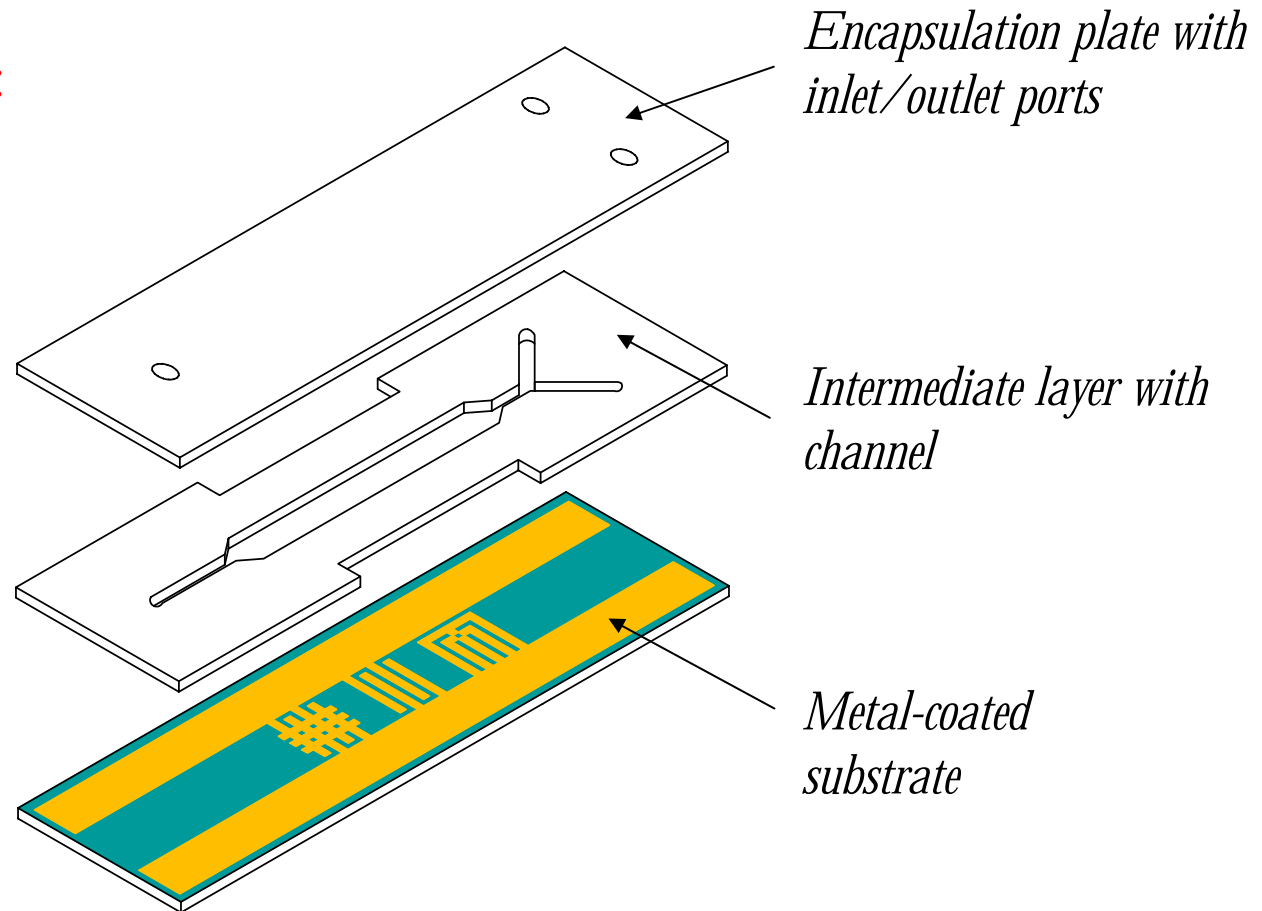
PROTOTYPE CHIP - DESIGN

Typical chip contains:

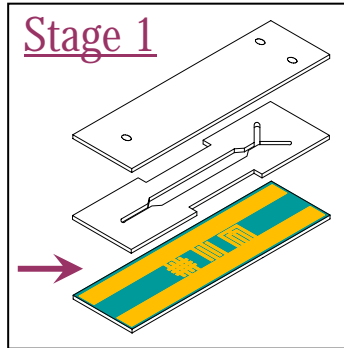
- Micro-electrodes
- Micro-channels
- Micro-holes
- Micro-optics

Common Materials:

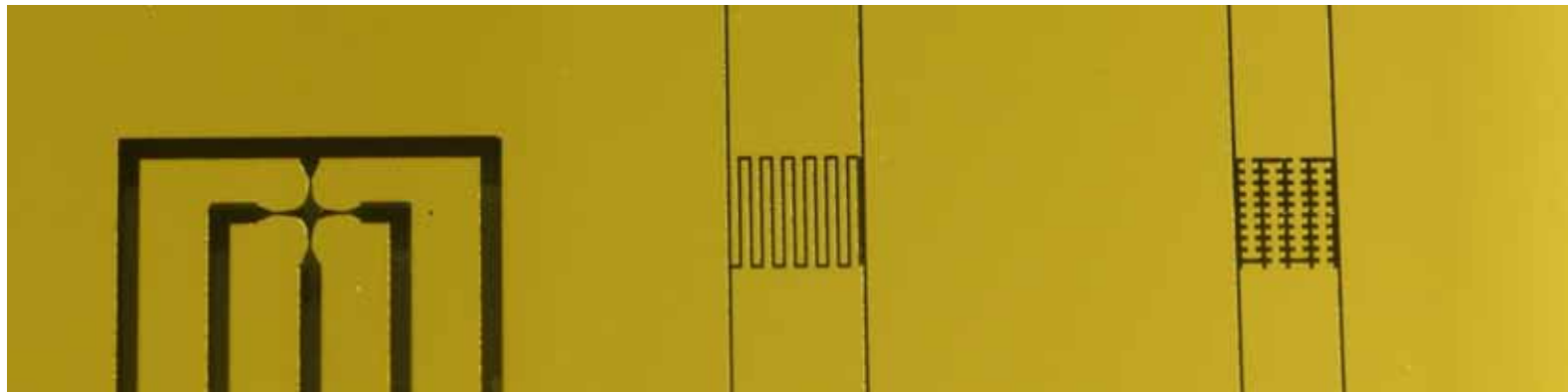
- Polymers
- Thin metal film
- Glass
- Composites



ELECTRODE LAYER



- 100nm gold on PC (glass is also commonly used)
- Various electrode designs for different functions
- UV laser patterning used to remove gold from substrate
- Different mask projection methods used depending on designs
- All masks made using laser cutting of polymers/metals

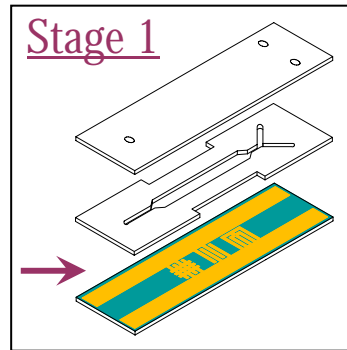


Polynomial electrodes

Levitation electrodes

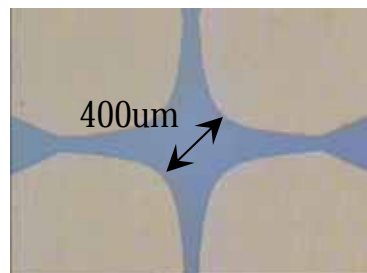
Castellated electrodes

PATTERNING OF ELECTRODES (1)



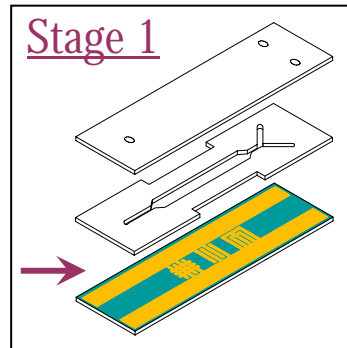
Details:

- Multiple masks used
- Mask dragging & synchronised mask scanning used



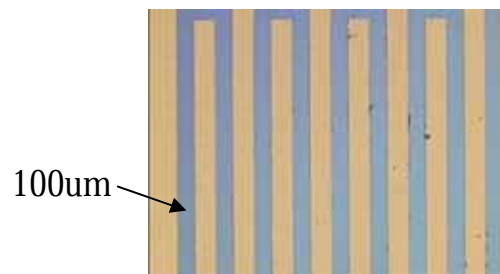
Polynomial Electrodes

PATTERNING OF ELECTRODES (2)



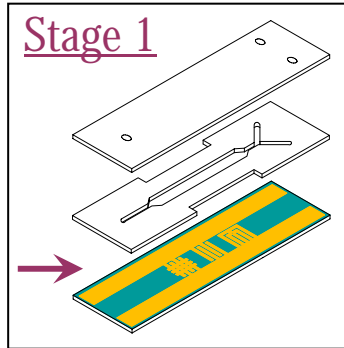
Details:

- Single mask used
- Mask dragging method produces sets of finger electrodes



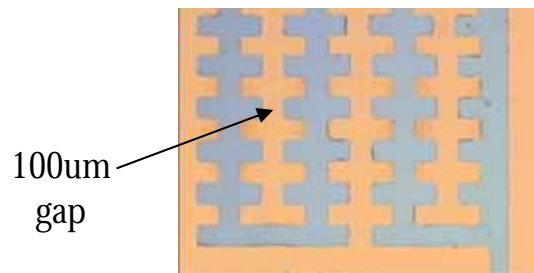
Levitation Electrodes

PATTERNING OF ELECTRODES (3)



Details:

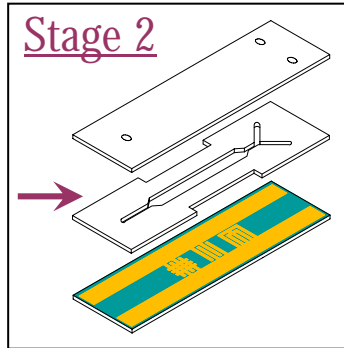
- Multiple masks used
- Step-and-Repeat method used to cover large area with repeating pattern



Castellated Electrodes



CHANNEL LAYER



- 250um thick polyester with adhesive on each side
- Different thickness can be used
- Typical channel widths range from 100um – 1mm
- Channel cut in polymer using direct writing

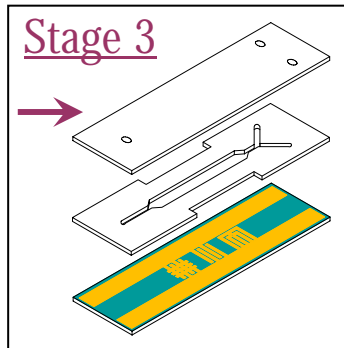


Channel layer after laser cutting

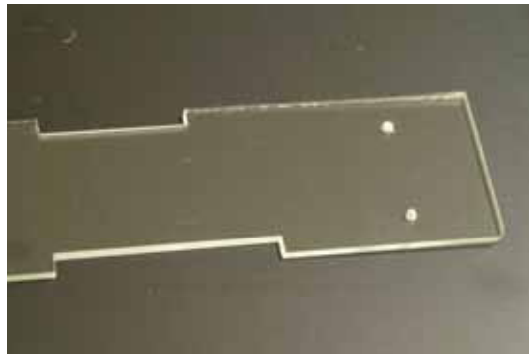


Example of high quality cutting of polyimide

ENCAPSULATION LAYER



- 1mm thick glass slide with through holes
- Different thicknesses can be used (down to ~50-100um)
- Typical holes size ~1mm (100um to 2mm holes also used)
- Holes cut in glass using direct writing
- Edges of glass also profiled to allow for electrical connections



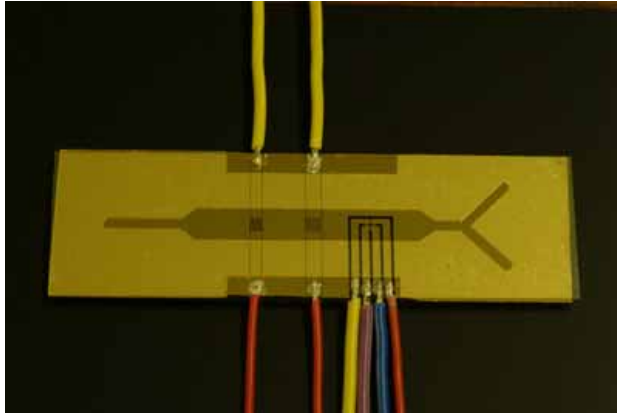
Glass slide after laser drilling and profiling



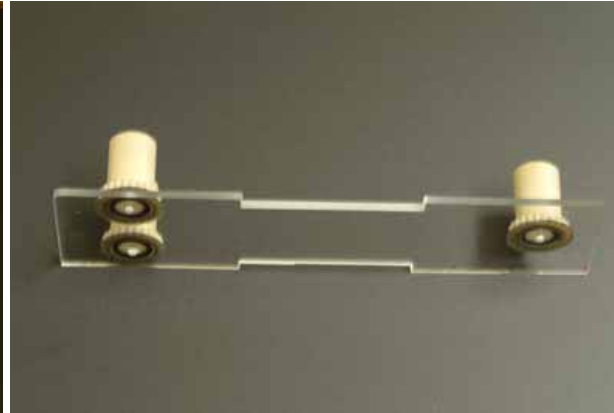
Example of high quality drilling of glass slide



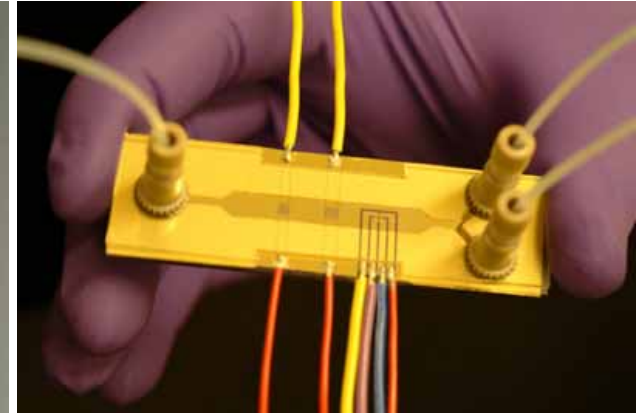
ASSEMBLY OF CHIP



- Electrical connections are made with electrodes.
- Continuity and shorting tests are conducted.
- Channel layer is aligned and bonded to electrode layer.

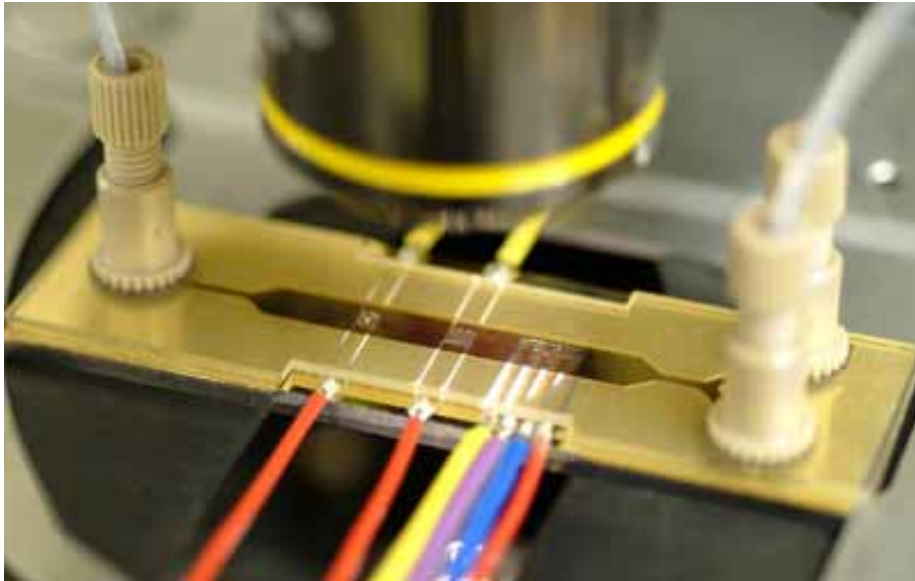


- Encapsulation layer is cleaned and port assemblies are prepared.
- Port assemblies are bonded over holes in glass.

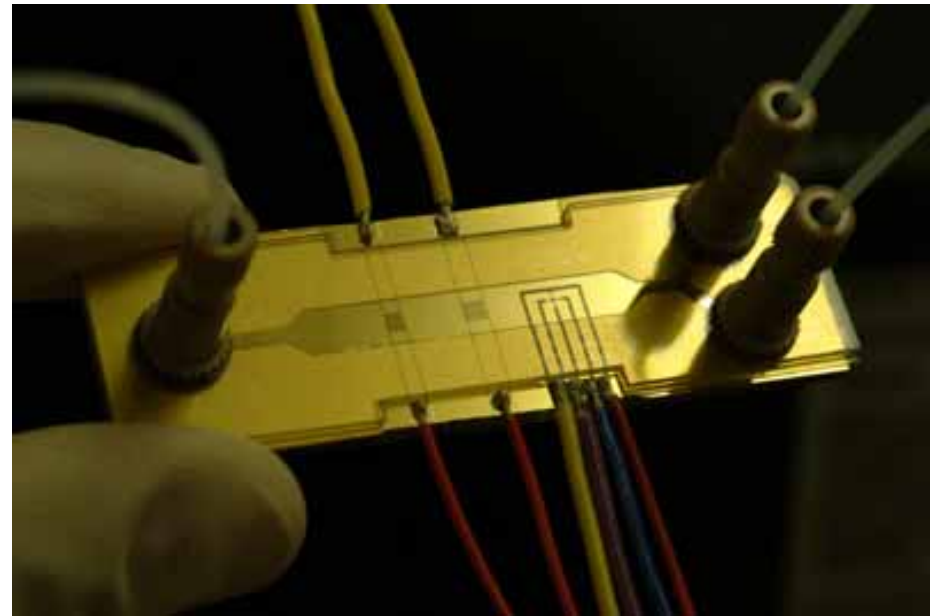


- Encapsulation layer and channel layers are aligned and bonded together.
- Complete chip is tested for leaks and flow.

COMPLETED DEVICE

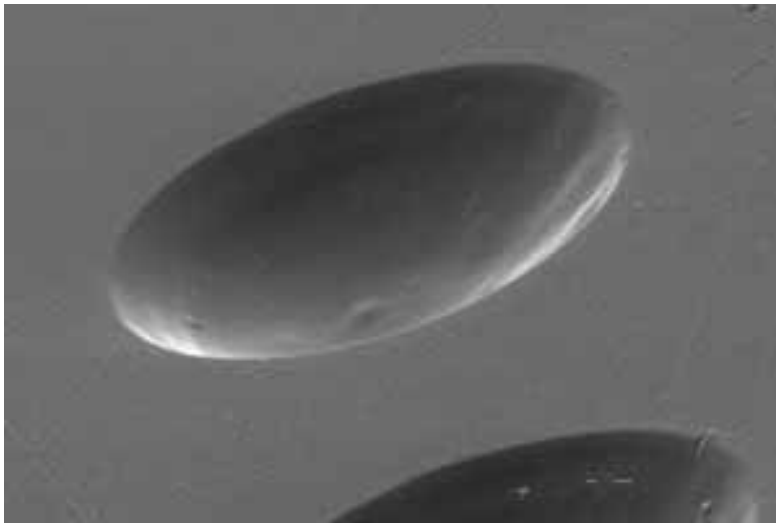


Assembled prototype device during final testing phase.



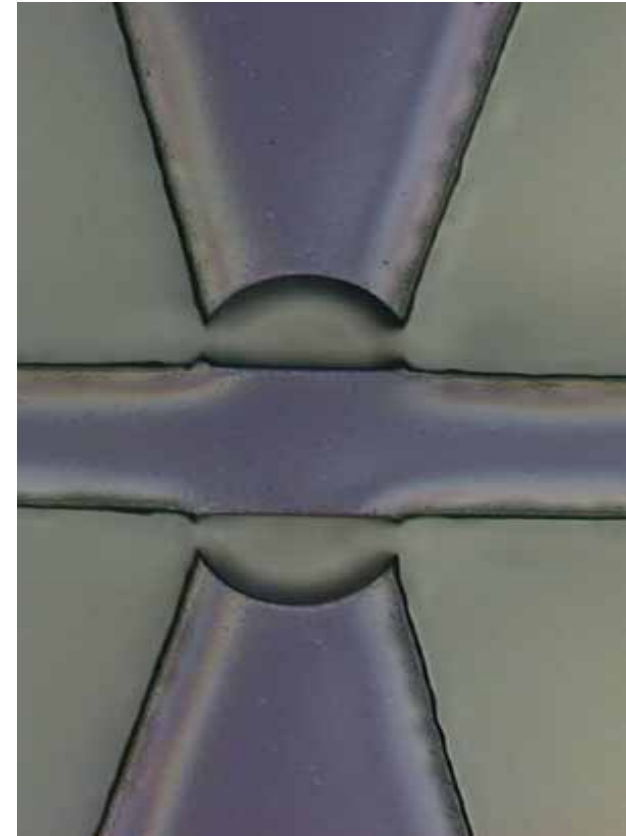
OPTICAL STRUCTURES

Devices can also incorporate optical elements (e.g. microlenses, waveguides) for interrogation of chip performance and enhanced functionality.



50um diameter microlenses in polycarbonate made with UV excimer laser.

Courtesy D.Morris & J.Burt, UWB (Optical Biochip project).



100um wide waveguide with lenses on each side, machined in polymer layer.

PROTOTYPE TO PRODUCTION

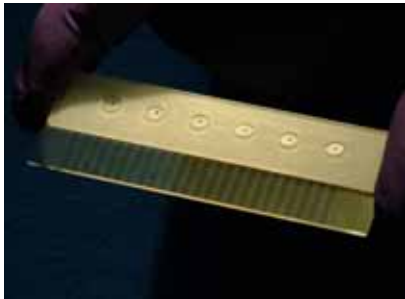
All elements of prototype chip can be automated for high volume production

- **Gold coating of substrates**
Batch process, can be made on wafer scale.
- **Patterning of electrodes**
High-speed laser patterning (or photolithography).
- **Channel layer**
High-speed cutting of polymers (reel-to-reel system).
- **Encapsulation layer**
Cutting and drilling using high power (speed) lasers.
- **Alignment & bonding**
Automated pick and place equipment can assemble devices.
- **Electrical connections**
Automated wire bonding.
- **Inlet/Outlet ports**
Automated handling and alignment systems place and bond.
- **Testing**
Fluidic and electrical tests can be conducted automatically.



Precision Laser Micromachining Services

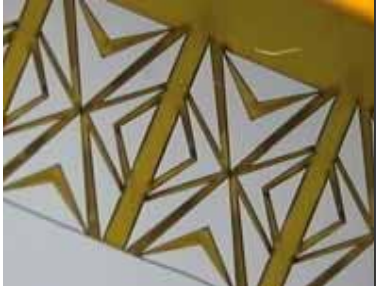
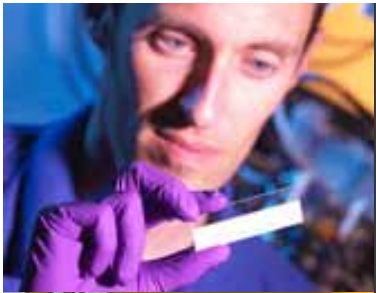
SUMMARY



The prototyping of a multi-level device has demonstrated:

- Ability of lasers to machine variety of materials and structures with high precision and quality.
- Great advantages of lasers during prototyping phases to evaluate designs quickly and cost-effectively.
- Implementation of multiple micromachining strategies in a single device to produce different features.
- Scalability – the process development work carried out can be used for automated manufacturing (i.e. laser processing is not ‘dead-end’).





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